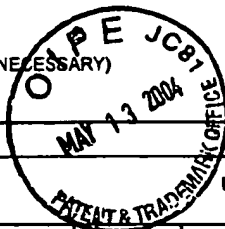


FORM PTO-1449	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY. DOCKET NO. ASMMC.052AUS	APPLICATION NO. 10/719,277
INFORMATION DISCLOSURE STATEMENT BY APPLICANT  (USE SEVERAL SHEETS IF NECESSARY)		APPLICANT Elers	
		FILING DATE November 20, 2003	GROUP 2811



## U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPROPRIATE)
<i>W</i>	1	4,450,472	5/22/84	Tuckerman et al.			
	2	4,938,742	7/3/90	Smits			
	3	5,218,515	6/8/93	Bernhardt			
	4	5,241,450	8/31/93	Bernhardt et al.			
	5	5,461,003	10/24/95	Havemann et al.			
	6	5,619,177	4/8/97	Johnson et al.			
	7	5,777,292	7/7/98	Grigorov et al.			
	8	5,901,037	5/4/99	Hamilton et al.			
	9	5,936,295	8/10/99	Havemann et al.			
	10	6,060,383	5/9/00	Nogami et al.			
	11	6,272,169 B1	8/7/01	Boswell, Jr. et al.			
	12	6,482,733	11/19/02	Raaijmakers et al.			
	13	6,534,395	3/18/03	Werkhoven et al.			
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	15	6,686,271	2/3/04	Raaijmakers et al.			
	16	6,699,783	3/2/04	Raaijmakers et al.			
	17	6,703,708	3/9/04	Werkhoven et al.			
	18	6,727,169	4/27/04	Raaijmakers et al.			12/15/03
	19	US 2003/0032281 A1	2/13/03	Werkhoven et al.			
<i>W</i>	20	US 2003/0143839 A1	7/31/03	Raaijmakers et al.			11/22/02

## FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
<i>W</i>	21	WO 98/03996	1/29/98	PCT				
	22	WO 98/03997	1/29/98	PCT				
	23	WO 98/04109	1/29/98	PCT				
<i>W</i>	24	WO 03/053895 A2	7/3/03	PCT				

EXAMINER <i>H. R. Anderson</i>	DATE CONSIDERED <i>6/9/04</i>
*EXAMINER: INITIAL IF CITATION CONSIDERED, WHETHER OR NOT CITATION IS IN CONFORMANCE WITH MPEP 609; DRAW LINE THROUGH CITATION IF NOT IN CONFORMANCE AND NOT CONSIDERED, INCLUDE COPY OF THIS FORM WITH NEXT COMMUNICATION TO APPLICANT.	

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(USE SEVERAL SHEETS IF NECESSARY)		FILE DATE November 20, 2003	GROUP 2811

EXAMINER INITIAL	OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)
<i>wp</i>	25 Blackburn, J.M. et al., "Deposition of conformal copper and nickel films from supercritical carbon dioxide," Science 294(5540) (2001) pp. 141-145
<i>wp</i>	26 Cabanas, A. et al., "Alcohol-Assisted Deposition of Copper Films from Supercritical Carbon Dioxide," J. Chemistry of Materials 15(15) (2003) pp. 2910-2916
<i>wp</i>	27 Dagani, Ron, "Dry Spinning of Carbon Nanotube Yarns"
<i>wp</i>	28 Kondoh, E. et al., "Characteristics of copper deposition in a supercritical CO <sub>2</sub> fluid," Microelectronic Engineering 64(1-4) (2002) pp. 495-499
<i>wp</i>	29 Lesiak, B. et al., "Characterization of Polyacetylene and Polyacetylene Doped with Palladium," Polish J. Chem., 74:847-865 (2000)
<i>wp</i>	30 J.-Q. Lü et al., Advanced Metallization Conference 2000 (ULSI XVI), pp. 515-521.
<i>wp</i>	31 Shirakawa, Hideki et al., "Synthesis of Electrically Conducting Organic Polymers: Halogen Derivatives of Polyacetylene, (CH) <sub>x</sub> ," J.C.S., Chem. Comm., 578-580 (1977)
<i>wp</i>	32 Tay, Andrew A.O., "Analytical Study on A MEMS Micro-Cooling System for Cooling of Flip Chips," Conf. on Design, Characterization, and Packaging for MEMS and Microelectronics, Queensland, Australia, Oct. 99, SPIE Vol. 3893, pp. 82-93
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EXAMINER <i>H. P. P. P.</i>	DATE CONSIDERED <i>4/9/05</i>
*EXAMINER: INITIAL IF CITATION CONSIDERED, WHETHER OR NOT CITATION IS IN CONFORMANCE WITH MPEP 609; DRAW LINE THROUGH CITATION IF NOT IN CONFORMANCE AND NOT CONSIDERED, INCLUDE COPY OF THIS FORM WITH NEXT COMMUNICATION TO APPLICANT.	